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Thick Polycrystalline Silicon For Surface Micromechanical Applications: Deposition, Structuring And Mechanical Characterization

Lange, P.; Kirsten, M.; Riethmuller, W.; Wenk, B.; Zwicker, G.; Morante, J.R.; Ericson, F.; Schweitz, J.A.

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Low temperature sacrificial wafer bonding for planarization after very deep etching

Spiering, V.L.; Berenschot, J.W.; Elwenspoek, M.; Fluitman, J.H.J.
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Process and design considerations for surface micromachined beams for a tuneable interferometer array in silicon

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Integration of surface-micromachined zinc oxide sensors in n-well CMOS technology

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Plasma planarization for sensor applications

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40	3784	(seal\$3) near15 (MEMS microelectro microstructure micromachin\$3 microfabricat\$3 micro)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/07/12 14:01
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dry<near>release

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1 A dry-release method based on polymer columns for microstructure fabrication

Mastrangelo, C.H.; Saloka, G.S.;

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